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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Fred E. Stanke et al.

Application No.: 09/533,613

Filed: March 22, 2000

For: APPARATUS FOR IMAGING
METROLOGY

Group Art Unit: 2877

Examiner: H.Q. Pham.

**RESPONSE TO OFFICE ACTION
MAILED AUGUST 14, 2002 AND
REQUEST FOR ONE-MONTH
EXTENSION OF TIME**

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San Francisco, CA 94105
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#15/EO+
T. 4/24/03
1-9-03

Commissioner for Patents
Washington, D.C. 20231

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, Washington, DC 20231 on December 13, 2002.

STALLMAN & POLLOCK LLP

Dated: 12/13/2002

By:

Georgia K. Stith
Georgia K. Stith

Sir:

In response to the Office Action mailed August 14, 2002, and in conjunction with Applicants' request for a one-month extension to time, please amend the above-identified application as follows:

IN THE SPECIFICATION:

On page 23, lines 1 to 8, please replace the first paragraph on the page with the following. Attachment A provides a marked up version of the changed paragraph.

Requested Change

21 --FIG. 9 shows a preferred embodiment integrated with a wafer process station in a fabrication line. For purposes of illustration and not limitation, the process station in the embodiment in FIG. 9 is a polisher. A polishing machine 1 and an integrated surface metrology station, ISMS 10, are shown. The polishing machine 1 comprises a polishing unit 14, loading

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Atty Docket No.: TWI-30200